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Embodiment	Wavelength λ	Polarization Φ	Propagation direction (θ, ϕ)	Diffraction order (m, n)	Profile	Seed model	Measurement mode	
1	Range	Fixed	Fixed	Fixed	Symmetric	Yes	Transmitive	
2	Range	Fixed	Fixed	Fixed	Symmetric	No	Transmitive	
3	Fixed	Fixed	Range	Fixed	Symmetric	Yes	Transmitive	
4	Fixed	Fixed	Range	Fixed	Symmetric	No	Transmitive	
5	Range	Fixed	Fixed	Multiple	Symmetric	Yes	Transmitive	
6	Range	Fixed	Fixed	Multiple	Symmetric	No	Transmitive	
7	Fixed	Fixed	Range	Multiple	Symmetric	Yes	Transmitive	
8	Fixed	Fixed	Range	Multiple	Symmetric	No	Transmitive	
9	Range	Fixed	Fixed	Multiple	Asymmetric	Yes	Transmitive	
10	Range	Fixed	Fixed	Multiple	Asymmetric	No	Transmitive	
11	Fixed	Fixed	Range	Multiple	Asymmetric	Yes	Transmitive	
12	Fixed	Fixed	Range	Multiple	Asymmetric	No	Transmitive	
13	Range	Fixed	Range	Multiple	Symmetric	Yes	Transmitive	
14	Range	Fixed	Range	Multiple	Symmetric	No	Transmitive	
15	Range	Fixed	Range	Multiple	Asymmetric	Yes	Transmitive	
16	Range	Fixed	Range	Multiple	Asymmetric	No	Transmitive	
17	Range	Fixed	Fixed	Fixed	Symmetric	Yes	Reflective	
18	Range	Fixed	Fixed	Fixed	Symmetric	No	Reflective	
19	Fixed	Range	Fixed	Fixed	Symmetric	Yes	Reflective	
20	Fixed	Range	Fixed	Fixed	Symmetric	No	Reflective	
21	Range	Fixed	Fixed	Multiple	Symmetric	Yes	Reflective	
22	Range	Fixed	Fixed	Multiple	Symmetric	No	Reflective	
23	Fixed	Fixed	Range	Multiple	Symmetric	Yes	Reflective	
24	Fixed	Fixed	Range	Multiple	Symmetric	No	Reflective	
25	Range	Fixed	Fixed	Fixed	Multiple	Asymmetric	Yes	Reflective
26	Range	Fixed	Fixed	Fixed	Multiple	Asymmetric	No	Reflective
27	Fixed	Fixed	Range	Multiple	Asymmetric	Yes	Reflective	
28	Fixed	Fixed	Range	Multiple	Asymmetric	No	Reflective	
29	Range	Fixed	Range	Multiple	Symmetric	Yes	Reflective	
30	Range	Fixed	Range	Multiple	Symmetric	No	Reflective	
31	Range	Fixed	Range	Multiple	Asymmetric	Yes	Reflective	
32	Range	Fixed	Range	Multiple	Asymmetric	No	Reflective	

TABLE 1

BEST AVAILABLE COPY

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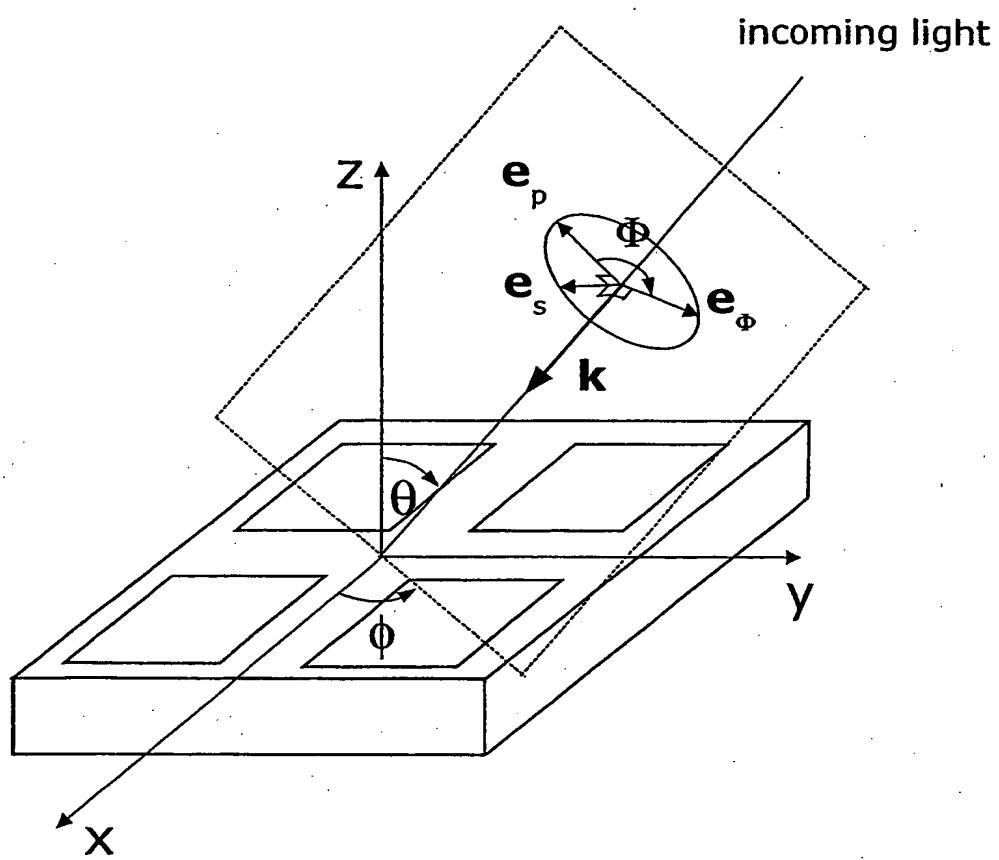
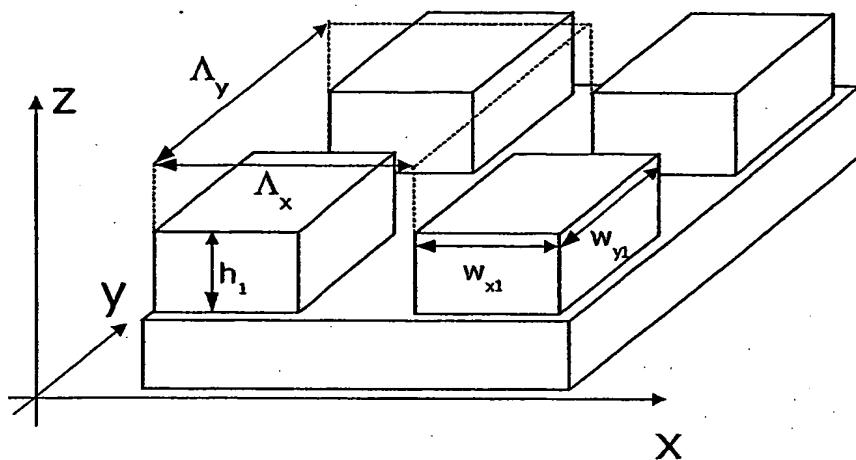


Fig. 1

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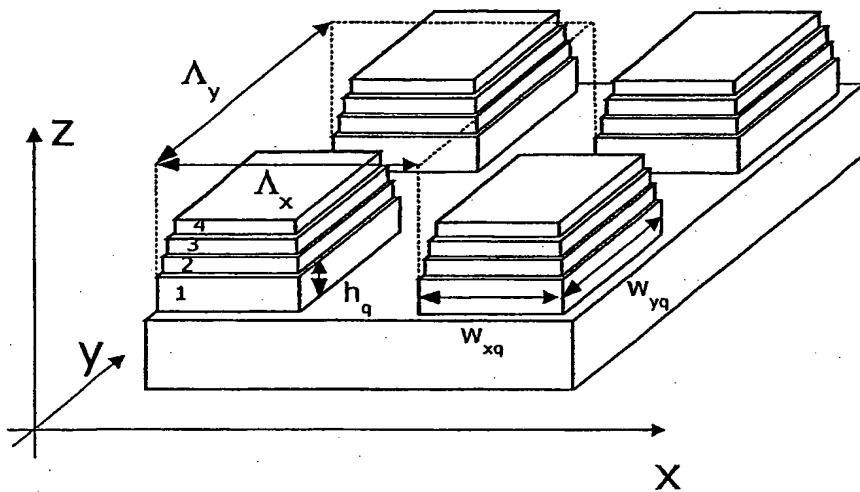


Layer q	Height h_q (nm)	Width		Offset		Material
		w_{qx} (nm)	w_{qy} (nm)	x_q (nm)	y_q (nm)	
Substrate	infinity	n/a	n/a	n/a	n/a	InP
1	290,00	180,00	125,00	0,00	0,00	Photo resist
Superstrate	infinity	n/a	n/a	n/a	n/a	Vacuum

Periodicity: $\Lambda_x = 300$ nm $\Lambda_y = 250$ nm

Fig. 2

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Layer q	Height h_q (nm)	Width		Offset		Material
		w_{qx} (nm)	w_{qy} (nm)	x_q (nm)	y_q (nm)	
Substrate	infinity	n/a	n/a	n/a	n/a	InP
1	200,00	180,00	125,00	0,00	0,00	Photo resist
2	30,00	179,79	122,82	0,00	0,00	Photo resist
3	30,00	176,61	120,25	0,00	0,00	Photo resist
4	30,00	167,01	117,65	0,00	0,00	Photo resist
superstrate	infinity	n/a	n/a	n/a	n/a	Vacuum

Periodicity: $\Lambda_x = 300$ nm $\Lambda_y = 250$ nm

Fig. 3

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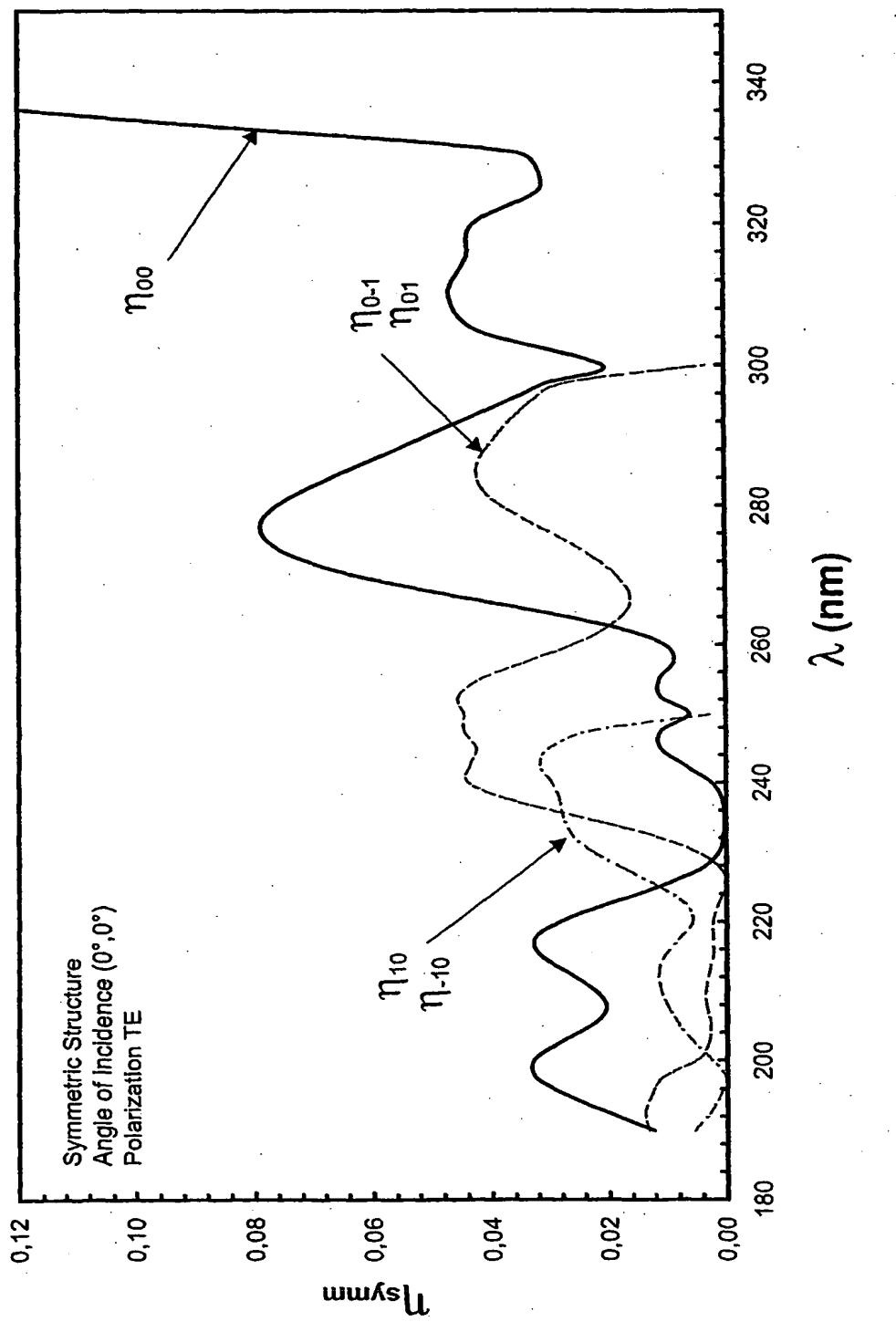


Fig. 4

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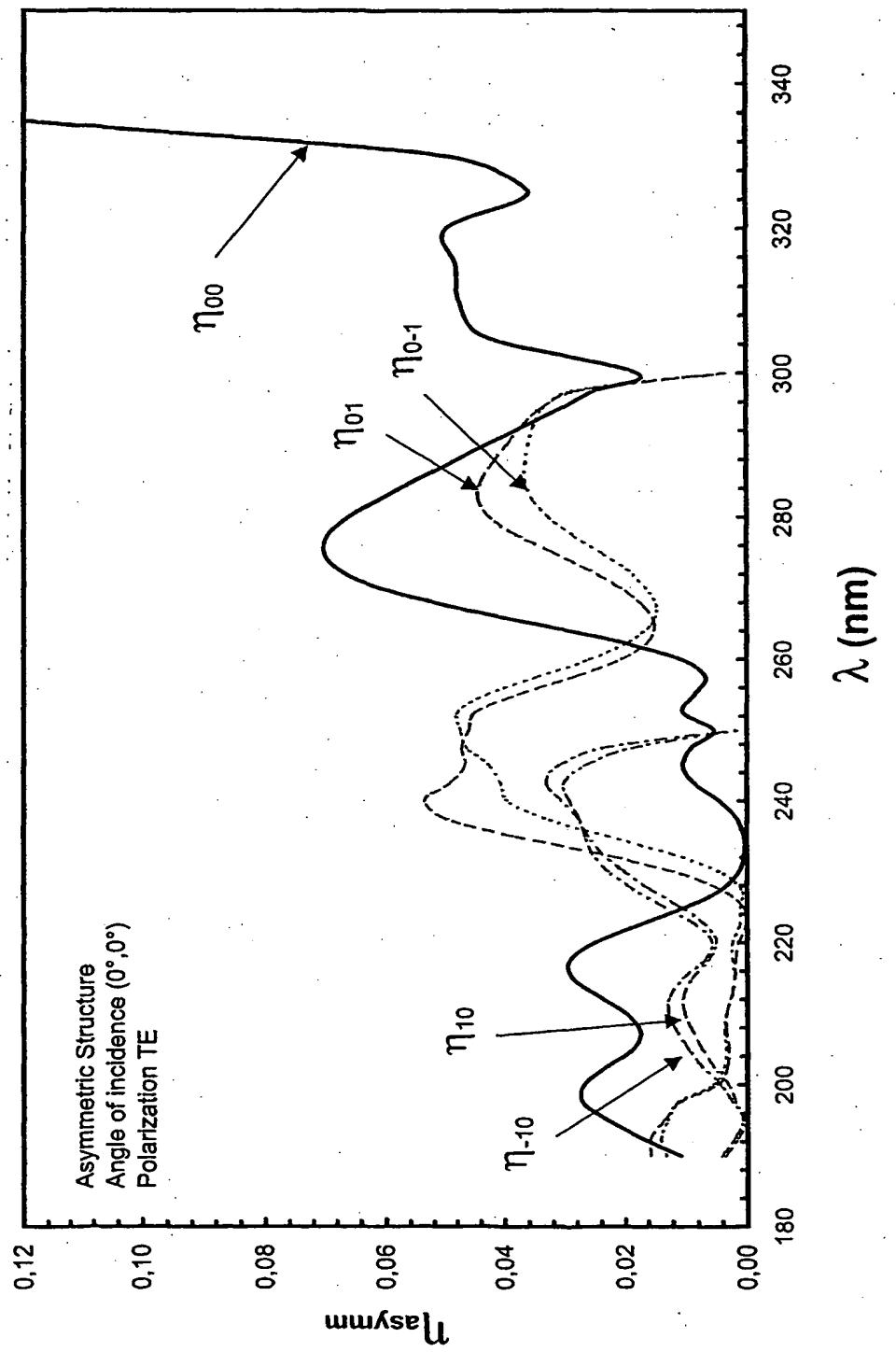


Fig. 5

10/521009

Title: METHOD AND APPARATUS FOR
OPTICALLY MEASURING THE TOPOGRAPHY OF
NEARLY PLANAR PERIODIC STRUCTURES
Inventor(s): Niels Agersnap LARSEN et al.
DOCKET NO.: 030307-0251

WO 2004/008069

DK2003/000457

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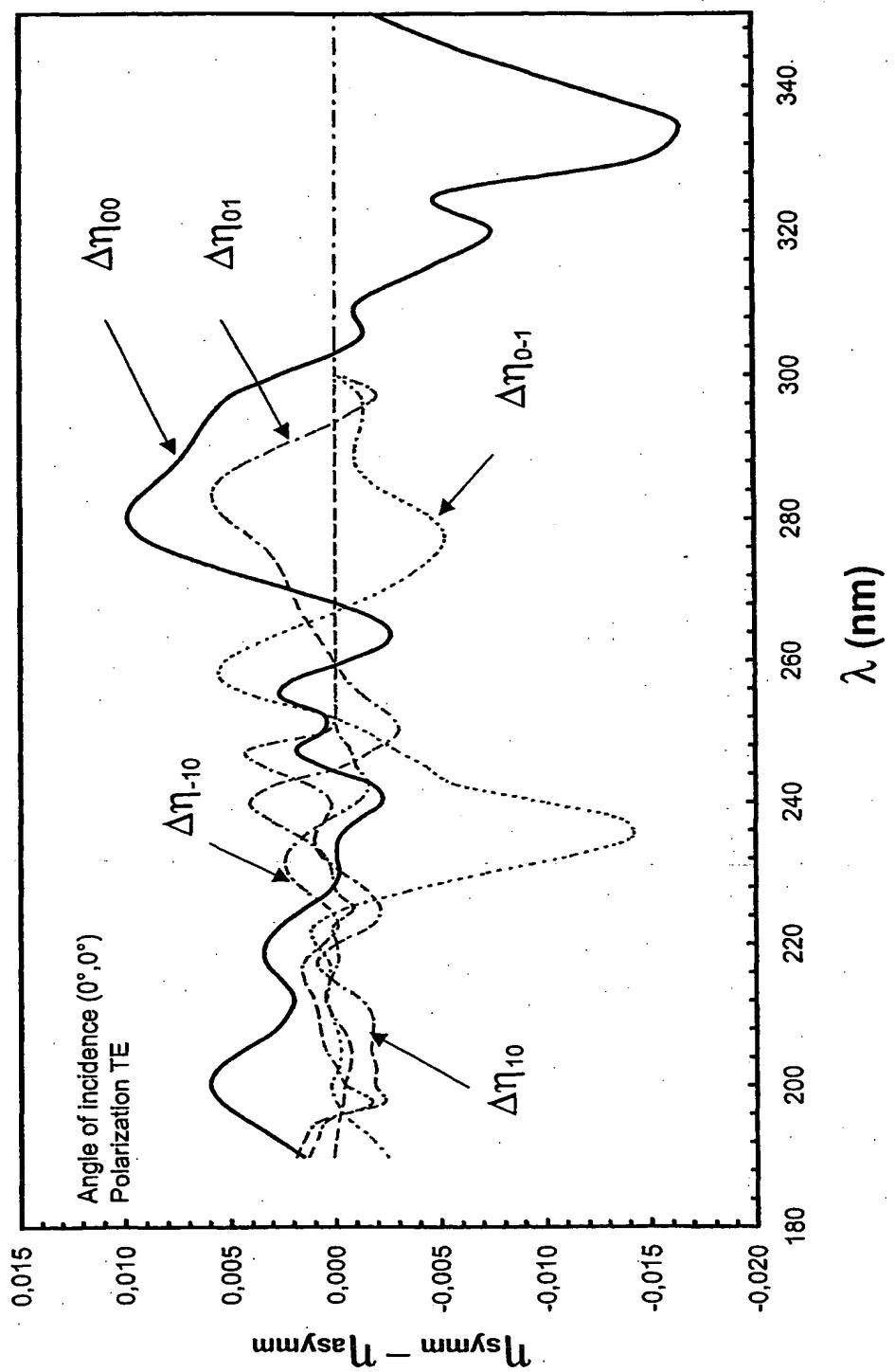


Fig. 6

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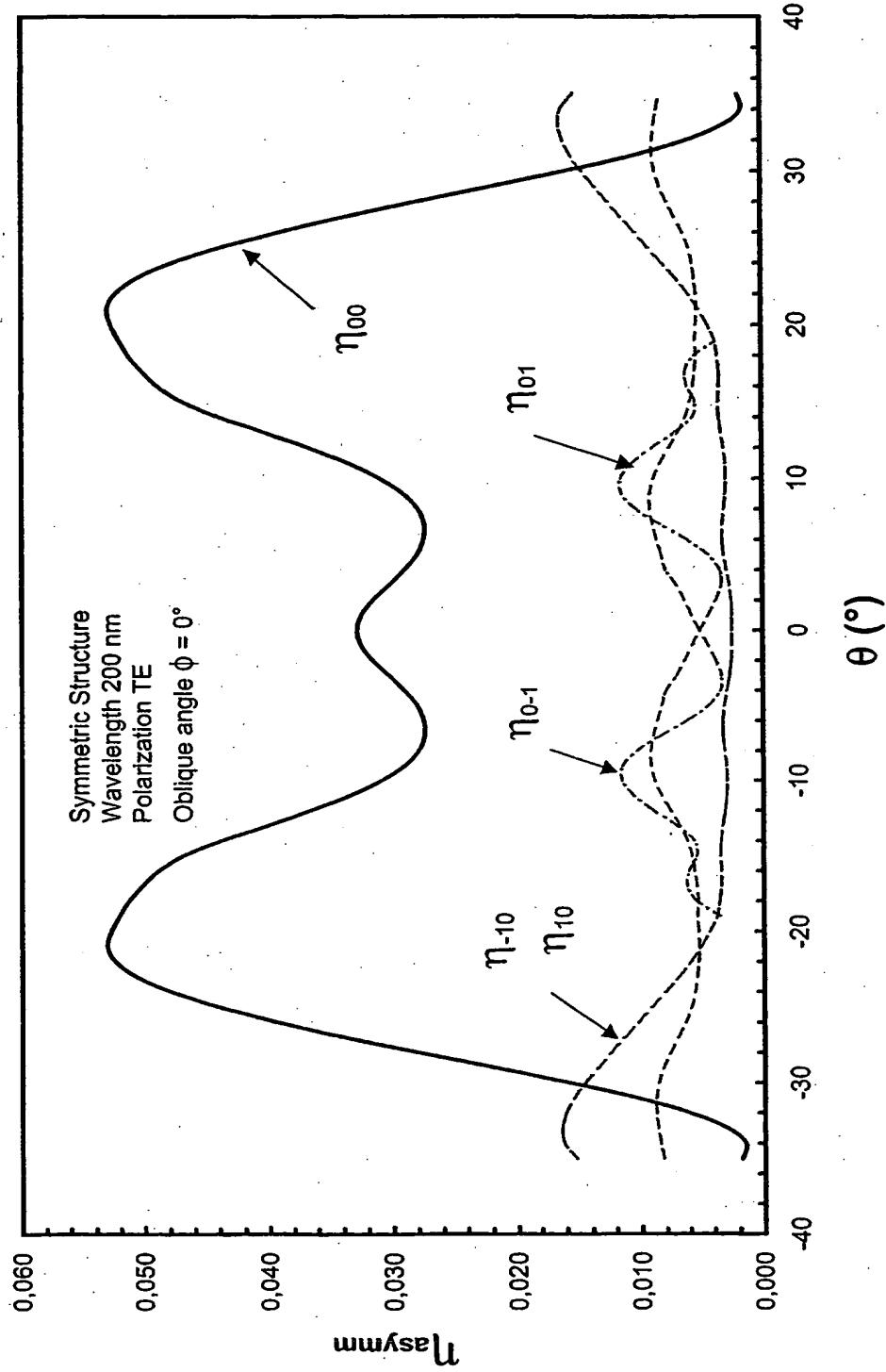


Fig. 7

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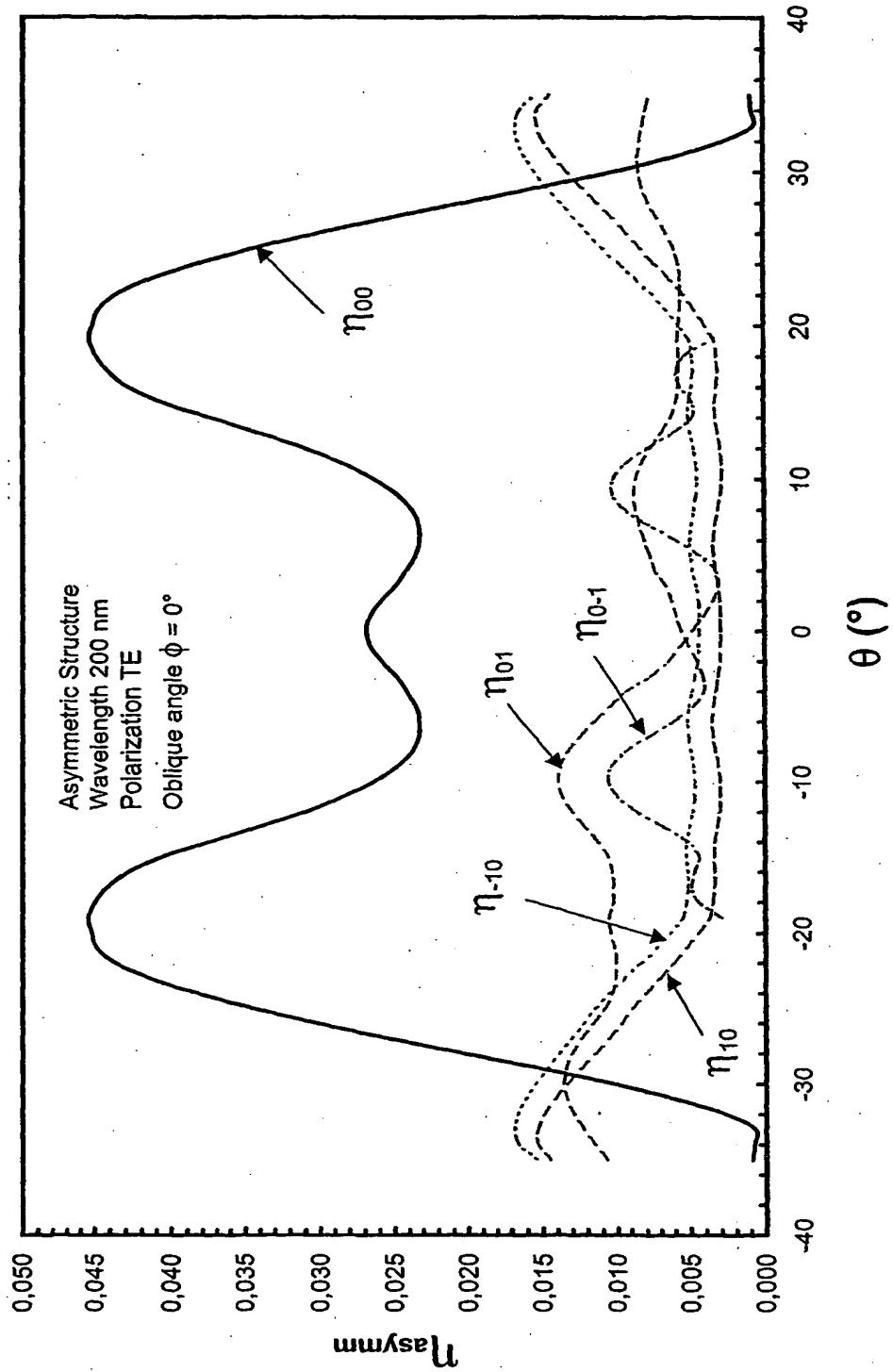


Fig. 8

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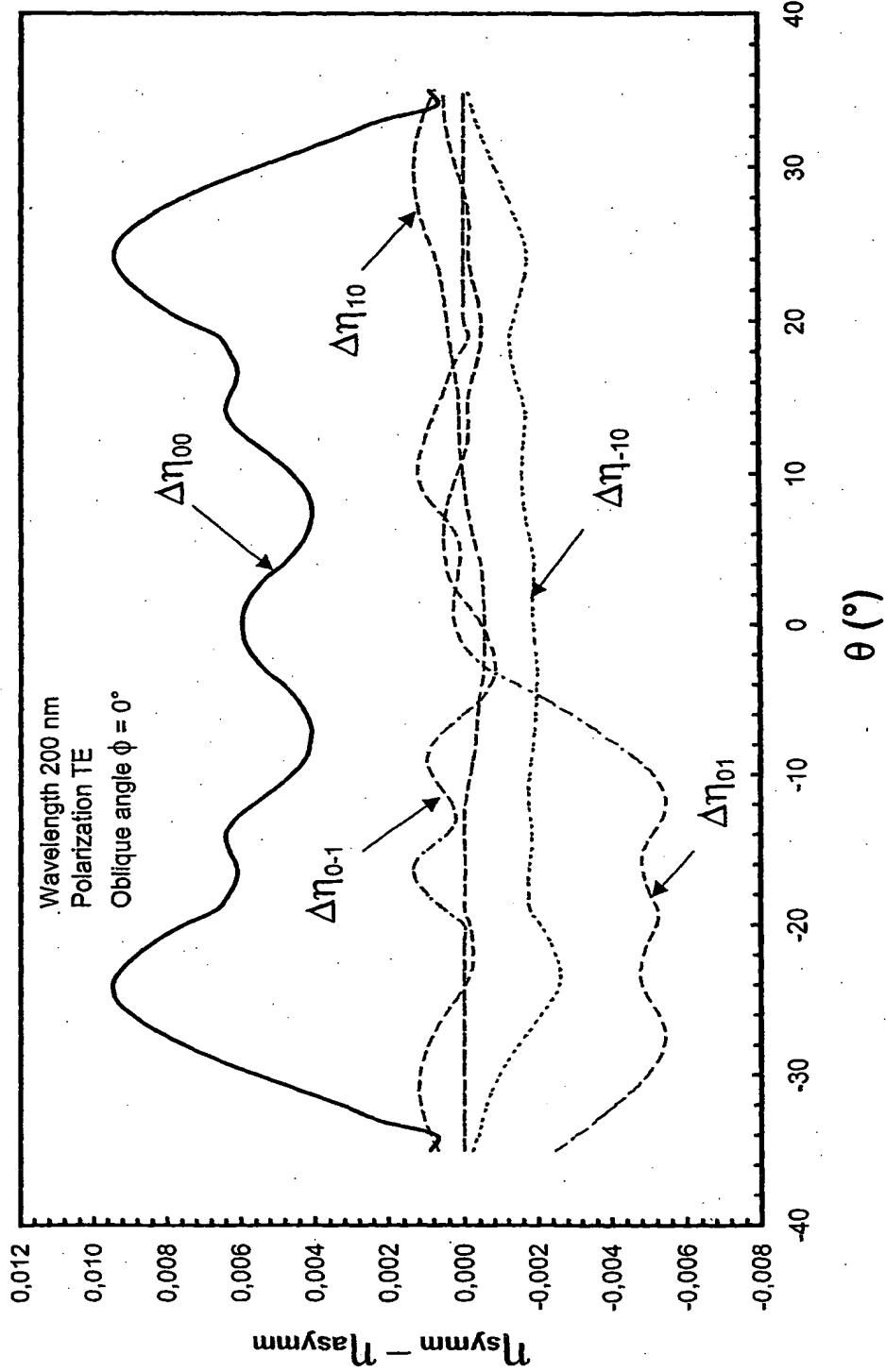


Fig. 9

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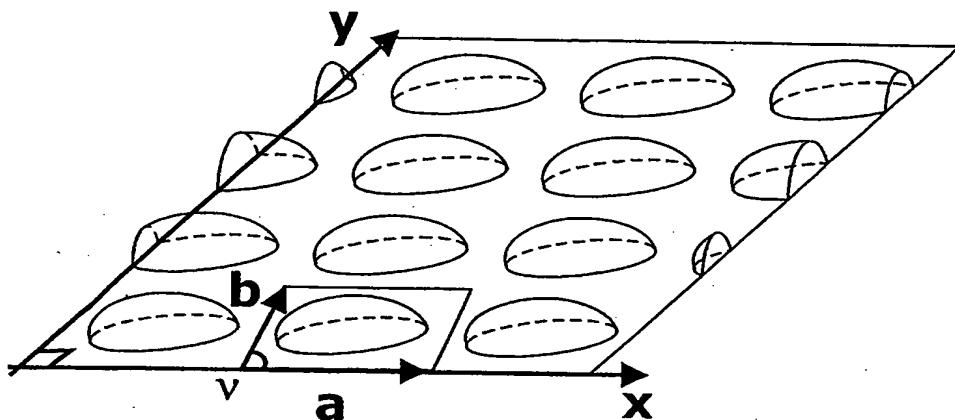


Fig. 10a

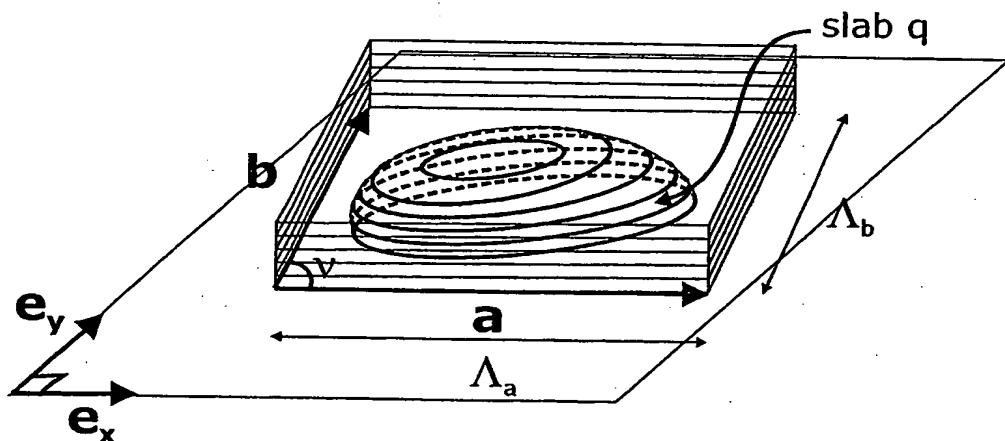


Fig. 10b

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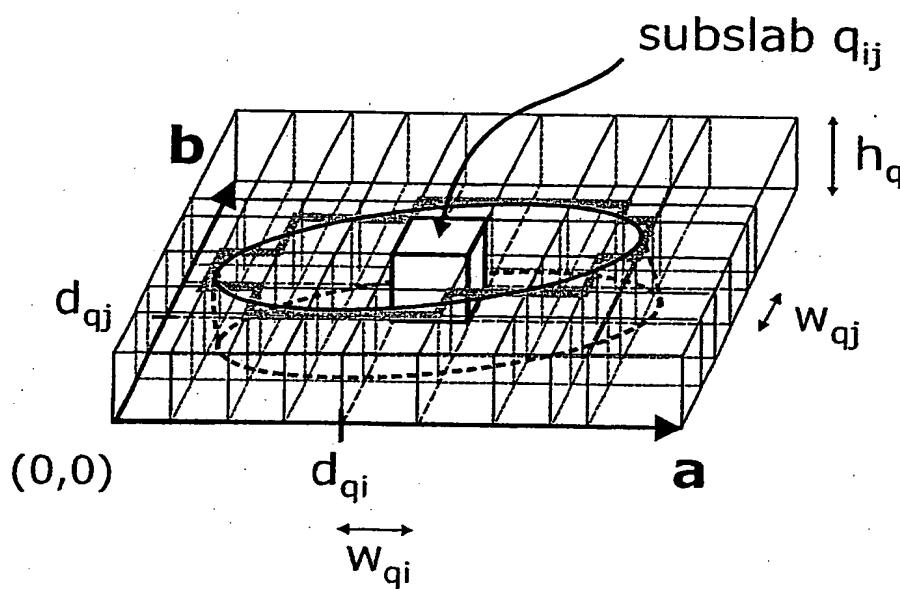


Fig. 10c

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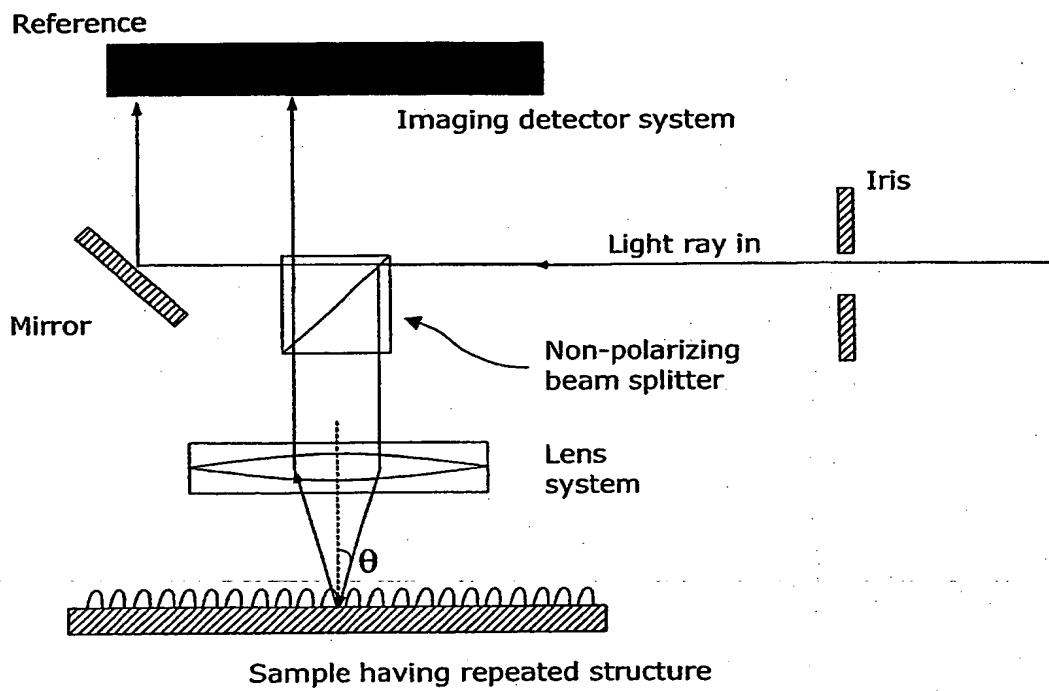


Fig. 11

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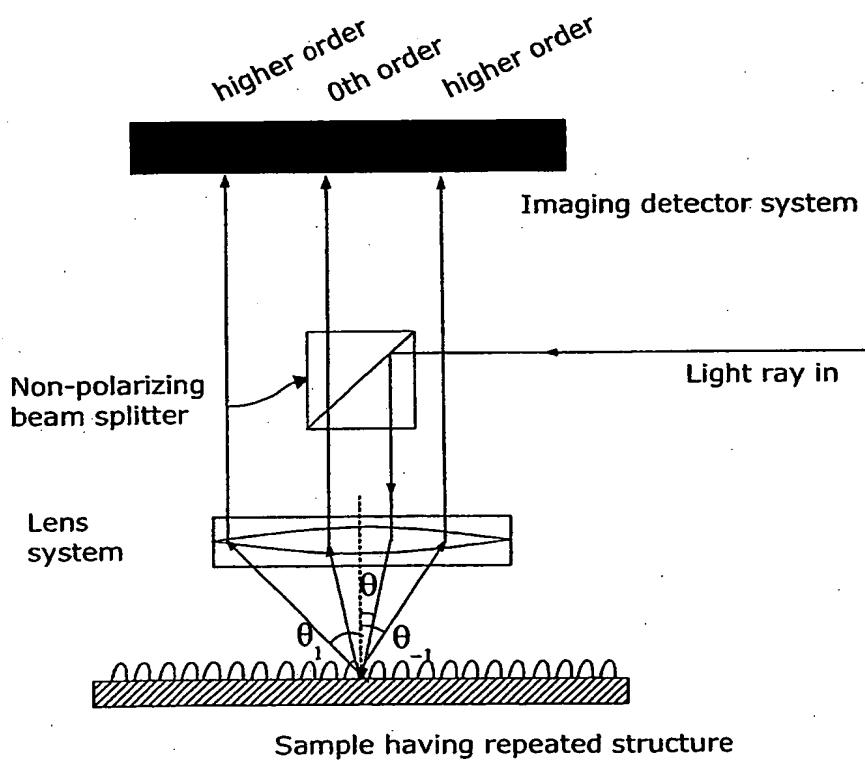


Fig. 12

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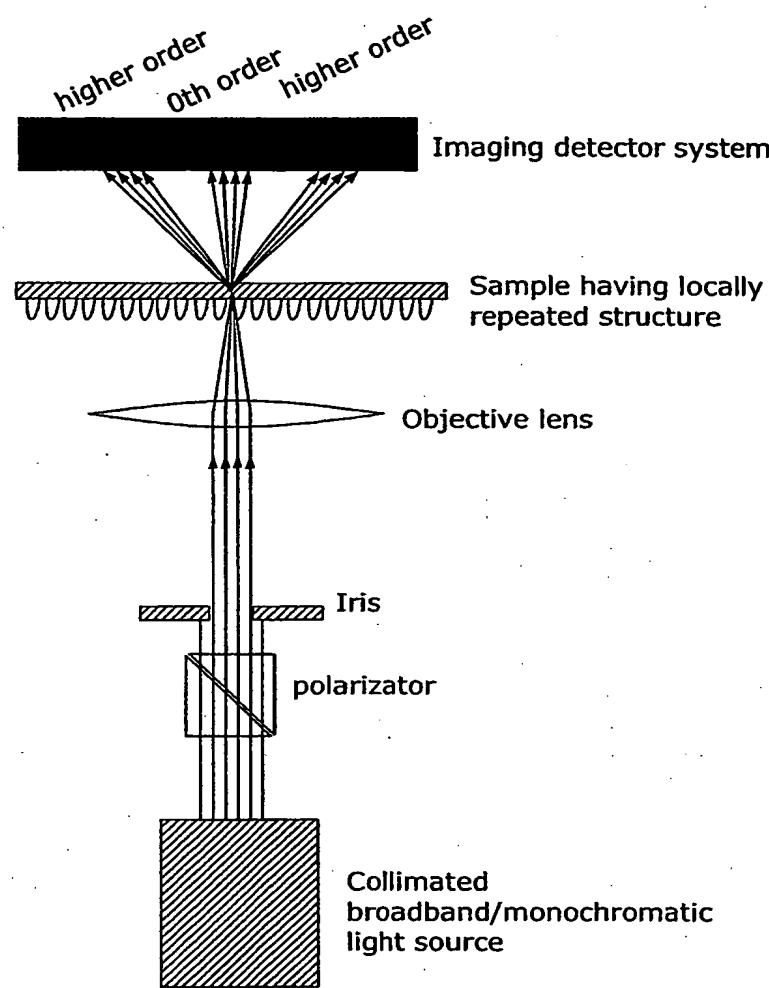


Fig. 13

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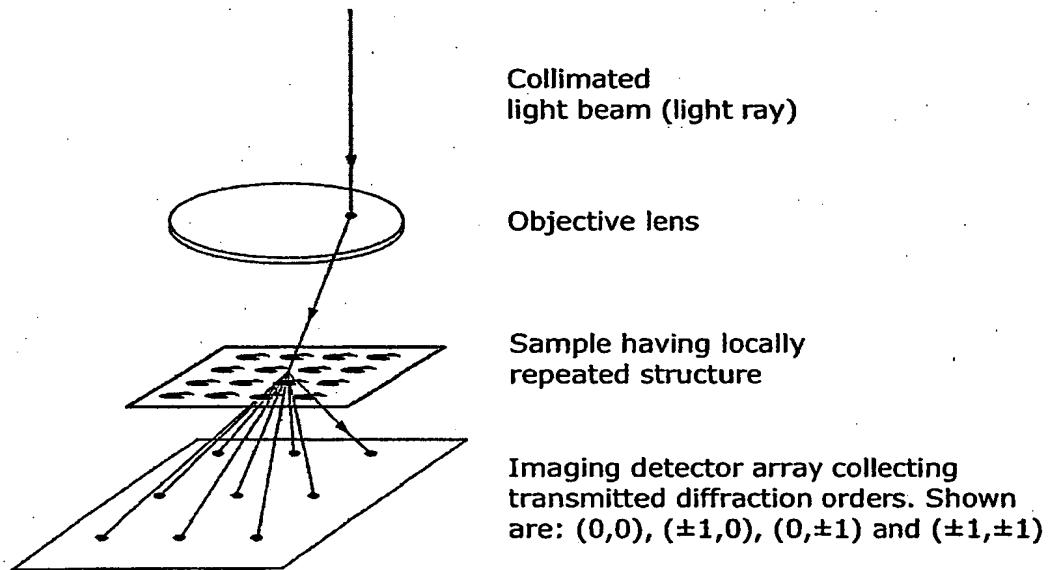


Fig. 14

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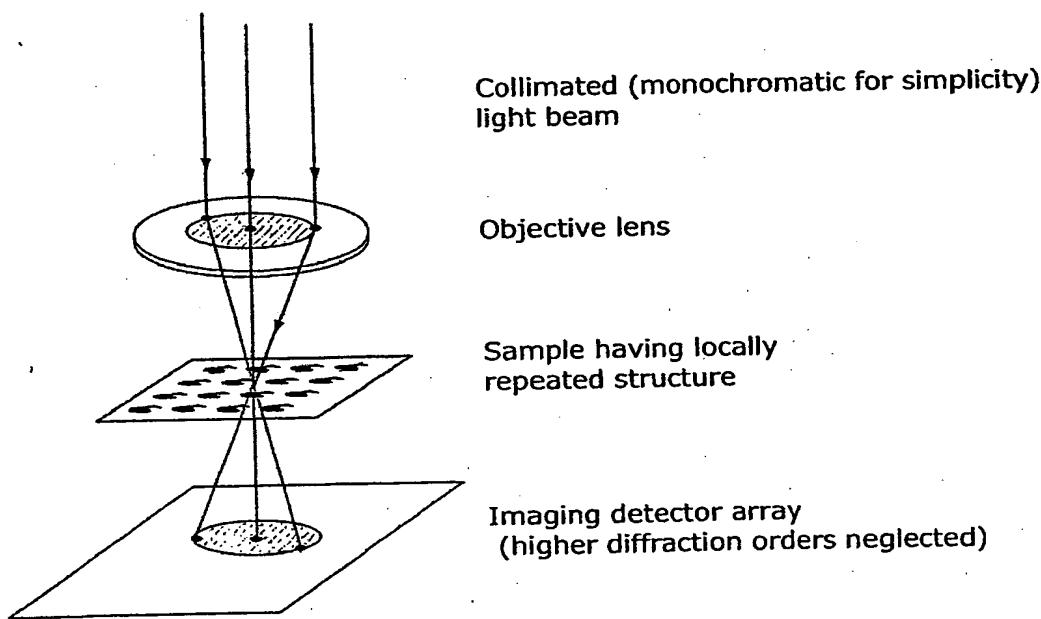


Fig. 15

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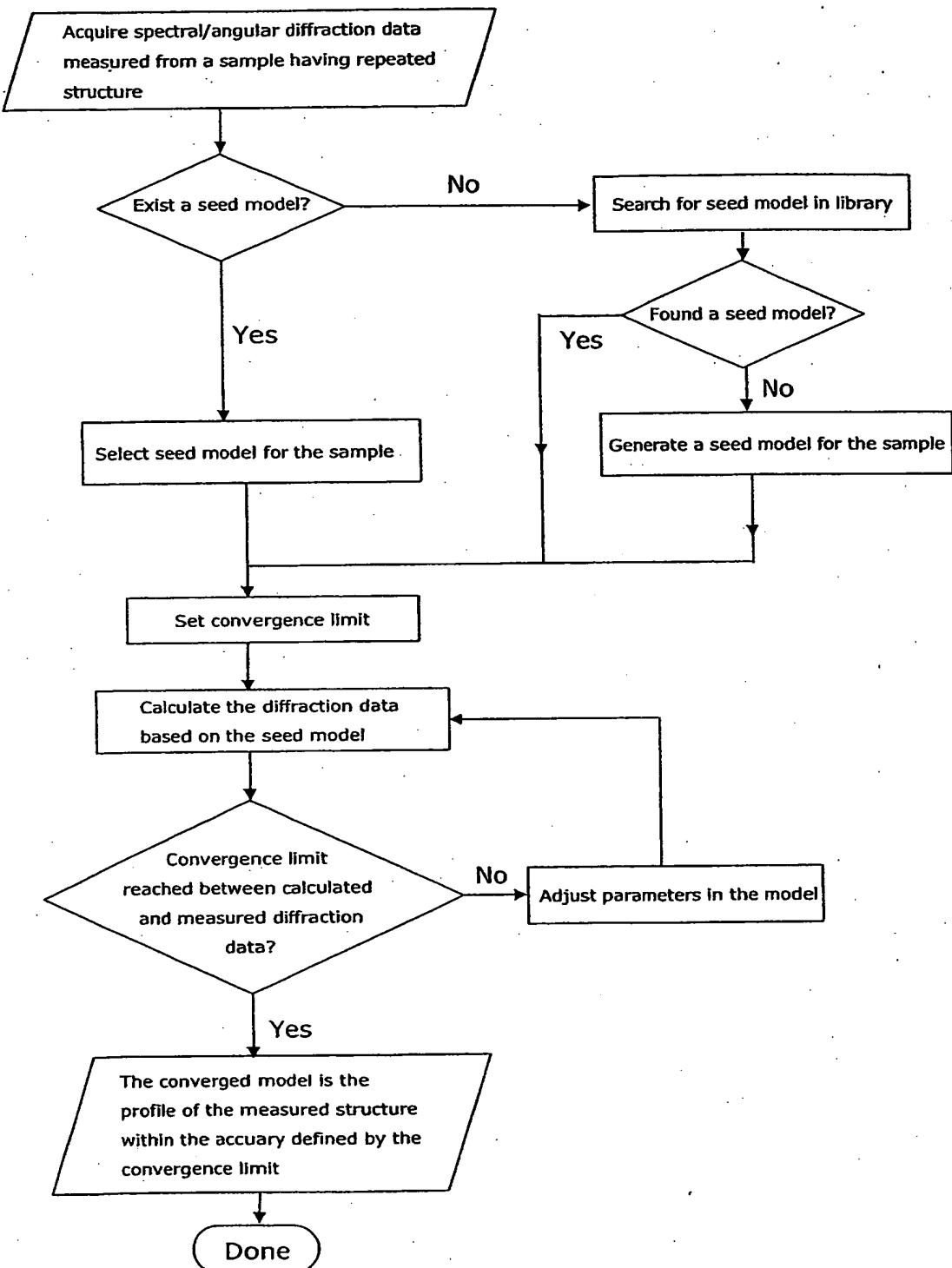


Fig. 16